# Modeling Tools for Solid Oxide Fuel Cell Analysis

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## **Modeling Project Overview**

## Motivation

- Objectives & Approach
- Project Accomplishments
- Collaborations
- Overview of Modeling Tools
- Conclusions & Ongoing Work



# **Motivation**

- The SOFC is a complex system:
  - Multiple physical phenomena including fluid flow, electrochemistry, electric fields, thermal field, mechanical deformations, materials compatibility
  - Physical phenomena are tightly coupled (i.e. not independent)
  - High operating temperature range
- SOFC testing is very expensive:
  - Characterization of material properties, stability, and performance required
  - Stack fabrication, assembly, monitoring, and testing are time intensive
  - Only a minimal number of experimental tests can be done to validate long term technical performance targets (e.g. 10,000 hr)
- Modeling can be used for numerical design experiments:
  - Can simulate the multiple physical phenomena
  - Can be used repetitively to quickly evaluate the effects of design changes or explore the viable design space
  - Can be used in conjunction with testing to optimize performance
  - Can investigate long term behaviors



# **Objectives & Approach**

### **Objectives**

- Develop integrated modeling tools to:
  - Evaluate the tightly coupled multi-physical phenomena in SOFCs
  - Aid SOFC manufacturers with materials development
  - Allow SOFC manufacturers to numerically test changes in stack design to meet DOE technical targets
- Support industry teams use of modeling for SOFC development
- Provide technical basis for SOFC stack design
- Disseminate/transfer modeling tools to SECA industry teams and CTP members

## Approach

- Multiphysics-based analysis tools coupled with experimental validation:
  - SOFC-MP: A multi-physics solver for computing the coupled flowthermal-electrochemical response of multi-cell SOFC stacks
  - Targeted modeling tools for specific cell design challenges:
    - Reliable sealing
    - Durable interfaces
    - Cathode contact paste durability
    - Pressurized operation for large stacks
    - Secondary reactions
- Collaboration with NETL, ORNL, and ASME to establish a stack design approach

# **Project Accomplishments**

- Continued to promote and support the use of SOFC-MP and Mentat-FC software packages with industry teams and CTP university teams
- Enhanced calculation speed and efficiency of SOFC-MP and porting to multiple platforms
- Developed a stack calculator (2D SOFC-MP) that quickly solves the temperature distribution and is suitable for incorporation into a system level model.
- Completed first-of-a-kind design guide for SOFCs
- Implemented time dependent constitutive model for glass seal materials in stack simulations.
- Developed a modeling capability to evaluate densification and strength of cathode contact materials, load path, and residual stresses due to stack assembly processes.
- Investigated the effect of oxide growth and metallic IC surface quality on interfacial strength of oxide scale and substrate.
- Developed a model to include creep of SOFC materials and to examine the effect on stress distribution with the stack components.
- Added elevated pressure capability to the EC and reforming models and examined effects on performance of large stacks.

## Collaborations

PNNL modeling staff are currently collaborating with SOFC researchers on several technical issues

- ASME design document
  - ORNL: E Lara-Curzio, Y Wang, A Shyam
  - ASME: J Powers, R Swayne
- Contact paste characterization
  - ORNL: E Lara-Curzio, Y Wang
  - NDSU: L Pederson
- Interconnect coatings
  - PNNL: J Stevenson
- SECA test cell
  - PNNL: J Stevenson, M Chou

- Modeling tool support
  - Delphi
  - Siemens
  - FCE
  - UCI: J Brower
- Seal characterization & modeling
  - PNNL: M Chou, J Stevenson
  - ORNL: E Lara-Curzio
  - GaTech: H Garmestani
- Secondary reactions
  - Carnegie Mellon: E Ryan
  - PNNL: O Marina
  - NDSU: L Pederson



# **SOFC-MP: Capabilities and Features**

- SOFC-MP Capabilities
  - 3D coupled flow, EC, and thermal solutions
  - Reduced order models for computational efficiency
  - Contact of incompatible meshes
  - Single or multi-cell models
  - Generic fuel and oxidants
  - Operation at assigned voltage, current, or fuel utilization
  - Thermal and electrochemical results output for visualization

- Recent Improvements
  - 2D version for symmetric stacks adapted from 3D SOFC-MP
  - Slice model computes results along stack centerline
    - Co/counter-flow only
    - Can handle many cells
    - Faster for parametric studies of large stacks
  - Computations
    - Current distribution
    - Voltage distribution
    - Thermal distribution
    - Species distribution
    - Heat losses







## **2D SOFC-MP- Stack Model Description**



- Geometric features
  - Co/Counter flow
  - Number of cells
  - Cell length/width
  - Thicknesses
  - Top/bottom plates
  - External insulation
- Thermal-EC properties
  - I-V curve parameters
  - Conduction, convection, and radiation parameters
- Assumption
  - Distributions are uniform in the lateral direction

## **2D SOFC-MP- Stack Model Description**



- Thermal model accounts for the coupled heat transfer modes of the fluid domains, solid components, and insulating enclosure
- Assumptions
  - Temperatures are uniform in the lateral direction
  - Currently, no explicit rib conduction link

## **2D SOFC-MP- Example Results**

- Example: counter-flow, 10 cm long cell, 30 cells, adiabatic
- Operation: 428 mA/cm<sup>2</sup>, 0.8 V, 65% UF, 15% UA
- 50% OCR Fuel: 0.324 H<sub>2</sub>, 0.333 H<sub>2</sub>0, 0.049 CO, 0.061 CO<sub>2</sub>, 0.110 CH<sub>4</sub>, 0.124 N<sub>2</sub>, 1 atm
- Air 0.21  $O_2$ , 0.79  $N_2$ , 1 atm



## **2D SOFC-MP- Example Results**

- Results
  - Cell min/average/max 667/742/802°C
  - Fuel in/out: 650/668°C
  - Air in/out: 650/753°C
- In summary, model is useful for more quickly characterizing large stacks





**Fuel Flow** 

Air Flow





## Modeling the Effect of Pressurization on Electrochemistry and Methane Reforming

## Background

- Pressurized operation increases electrochemical efficiency and thus decreases the net heat load
- On-cell steam-methane reforming is used effectively to decrease the heat load and is also affected by pressure

## **Objectives**

- Extend the SECA modeling capabilities to include the pressurization effects on the SOFC electrochemistry and on-cell steammethane reforming performance
- Incorporate the updated models into stack level tools to enable prediction of thermal and electrical performance of stacks operating at elevated pressure

## Approach

- Examine and model the coupled effects of pressurization on the SOFC electrochemistry, fuel gas composition, and reforming rates
- Validate model by parts (no public data for pressurized reforming operation of SOFC)
- Exercise the extended models on an example stack model to examine expected effects on thermal and electrical performance

# Effect of Pressure on Electrochemistry and Steam-Methane Reforming Rate

- Advanced SECA Electrochemical model considers activation polarization of both electrodes as described by the Butler-Volmer equation, which depends on the exchange current density (j<sub>o</sub>)
  - **PNNL** tests showed :  $j_o = j_o(PO_2^{0.5})$  for cathode
  - Others agree and find  $j_o = j_o(PO_2^{0.133})$  for the anode





The recently developed reforming <u>rate</u> <u>expression</u> considers effects of pressure on forward and reverse reaction, and maintains consistency with the literature, being 1<sup>st</sup> order in methane pressure, and with previous validated PNNL model



Equilibrium CH<sub>4</sub> concentrations

$$R_{r} = C_{K} \left( (2.09e + 9) \exp\left(\frac{-E_{act}}{RT}\right) P_{CH_{4}} P_{H_{2}O} - (1.54e - 4) P_{CO} P_{H_{2}}^{3} \right) \qquad C_{K} = (4.8e - 7) \exp\left(\frac{-1.45e4}{RT}\right) \quad \text{Pacific Northwest}$$

## Effect of Pressurization on Performance: Simulations of 20x20 cm Cross-Flow Stack

- Reforming rate near fuel inflow increased with pressure to a maximum at 7.5 atmospheres limited by available CH<sub>4</sub>
  - Low fuel utilization would support further rate increase
  - CH<sub>4</sub> concentration mirrored the reforming rate being decreased when the local rate was high
- Reforming rates varied downstream, as effected by the electrochemistry, depending on concentration and temperature
- Maximum temperature and ∆T decreased for operating pressures above 2.5 atmospheres
- Electrical performance increased steadily with increased operating pressure



 Pressure, atm
 Cell Voltage

 1.0
 0.653

 2.5
 0.678

 5.0
 0.690

 7.5
 0.717

 10.0
 0.721

Cell voltage as a function of operating pressure



Reforming rate and CH4 concentration near fuel inflow as a function of operating pressure



Reforming rate along the anode as a function of operating pressure

Temperature along the anode as a
 function of operating pressure

## **Modeling of Contact Paste and Load Path**

#### **Technical Drivers**

How does the interconnect geometry and contact paste layer affect load path and stresses in the stack?

#### **Technical Approach**

- Stack simulations to evaluate seal loads and stresses due to contact layer and interconnect features
- How does in-stack densification affect the load path and stresses in the stack?
  Stack simulations with densification strains for the contact paste layer
- What are the mechanical properties of the contact paste?
  Expendent
- Experimental testing at PNNL/ORNL and literature
- How much in-stack densification of the contact paste can be achieved to increase its strength?
- Combined materials model development and modeling effort

## 1. Stack Load Path Concept of Seal Load Reduction



# 1. Stack Load Path Results: Effect of IC Thickness/Creep

- Thicker interconnects with good cathode contact bonding were demonstrated to beneficially decrease the stresses in the perimeter glass-ceramic seal
  - Seal interface shear stresses less than experimental strengths, but localized seal and interface normal stresses predicted to be too large
  - Creep deformations of IC's also caused seal stress increase

IC Thickness (mm)	s <sub>vm</sub>	s <sub>11</sub>	s <sub>22</sub>	s <sub>33</sub>	s <sub>12</sub>	s <sub>23</sub>	S <sub>31</sub>
H=0.5	39.7	46.7	40.1	50.2	6.81	7.73	6.58
H=1.0	38.4	44.7	38.8	47.7	6.73	7.02	6.54
H=1.5	37.2	43.1	37.8	45.7	6.57	5.37	7.25
R (%)	6.7	8.4	6.1	9.8	3.7	43.9	10.9

#### PEN seal stresses decrease with IC thickness

PEN seal interface stresses decrease with IC thickness

IC Thickness (mm)	X-N-XX	X-P-XX	Y-N-YY	Ү-Р-ҮҮ
H=0.5	356	315	272	390
<b>H=1.0</b>	336	297	251	374
H=1.5	326	294	240	368
R (%)	9.2	7.2	13.3	6.0

## 2. Cathode Contact Paste Modeling Impacts of Densification on SOFC

- Densification is necessary to improve the mechanical properties of contact pastes
  - Higher density provides a higher elastic modulus
  - Higher density provides a higher strength and fracture toughness
- Densification in the cell causes volumetric changes that may be important for good contact
  - In-plane constraint causes higher out-of-plane strains
  - Glass-ceramic seals also experience volumetric changes due to devitrification
  - Will the contact paste/seals form correctly for strong bonds?
- Continuum constitutive model implemented for FEA evaluations



$$\sigma_{ij} = \frac{\sigma(W)}{W} \left[ \varphi \dot{\varepsilon}_{ij} + \left( \Psi - \frac{1}{3} \varphi \right) \dot{e} \delta_{ij} \right] + P_L \delta_{ij}$$

## 2. Cathode Contact Paste Modeling Results: Paste Densification

- Greatest volumetric shrinkage in the out-ofplane direction
  - Strains ~50X greater than in-plane directions due to lateral constraint of the cathode/IC rib
    - Same behavior as during electrolyte formation during co-firing
- Higher preload through the center cause enhanced sintering leading to relative density increase to 0.618
- The reduced sintering on the corners causes less densification to 0.604
- The corner region actually experiences tensile stresses during heat treatment that reverses the densification
- Preload distribution during paste formation determines final properties





#### Local loss of compression

## 2. Cathode Contact Paste Modeling Results: Loads and Stresses

- Models were evaluated with and without consideration of the densification strains in the contact paste layer
- With inclusion of densification strains:
  - Contact paste stresses increased slightly, but the maximum value was still less than the experimental strength (~1-14 MPa)
  - For the seal, in-plane shear loads decreased and out-of-plane normal loads were more compressive (to beneficially hinder delamination)
  - For the seal, in-plane peak stresses were not affected significantly while out-of-plane stresses were beneficially lower at operating temperature but unchanged at shutdown
  - Principal stresses in the anode/cathode/electrolyte layers were not significantly impacted by the contact paste densification at operating temperature or shutdown





## 3. Contact Paste Property Characterization

- Strength testing (PNNL, ORNL)
  - 1-14 MPa for spinel coated Crofer substrate/LSM-10
  - 2-8 MPa for Ce-spinel coated 441SS substrate/LSM-10
  - Average energy release rate of 1.47 Jm<sup>-2</sup> for spinel coated Crofer substrate/LSM-10
- Material challenges for inks and processing
  - Must ensure ink is calcined and attrition milled for good sintering
  - Must be cognizant of binder burn out rates to prevent void formation
- Currently, fabrication of 441SS specimens with the updated Ce-spinel coating is in progress
  - PNNL: Evaluate high versus low temp interfacial tensile specimens and compare to literature observations
  - ORNL: Evaluate the effect of porosity and thickness on interfacial fracture toughness. Evaluate thermal cycling and thermal aging.



Illustration of the crack propagation path observed at the spinel-paste interface for a fracture toughness specimen



Illustration of voids formed during fabrication of interfacial tensile specimens

## Lifetime Quantification of Coated Metallic Interconnects

#### **Current activities:**

- Quantifying adhesion strength between oxide and substrate for shot peened specimens
  - Bare shot peened 441 SS specimens are being oxidized in air at 850C for 600, 900, and 1200 hours
- Quantifying effects of shot peening on substrate surface:
  - Texture
  - Chemistry on grain boundary
- Quantifying delamination driving force with a shot peened surface
- Preparing Ce-doped spinel coated shot peened specimens

#### **Future activities:**

- Quantify interfacial strength of SS441/oxide for shot peened samples:
  - Surface finish
  - Residual stress
  - Surface chemistry/Grain boundary modification
- Quantify interfacial strength of Ce doped MC spinel/oxide for coated SS441 samples
- Life prediction for coated SS441
- Integrate ORNL measured growth stress in IC life prediction
- Optimization of coating thickness for SS441

## Accomplishment: Quantified Effects of Batch and Surface Quality on Oxide Adhesion upon Cooling

2007: First batch (left: as received, right: polished)



2008: Second batch (left: as received, right: polished)

Non-polished surface. Spallation observed



	First Batch		Second Batch		
Surface Condition	As- received	Polished	As- received	Polished	
Roughness	0.7	0.25	0.4	0.02	
Total Number of Specimens	3	4	3	3	
Number that Spalled	3	0	1	0	

- Different batches of as-received materials have different level of spallation tendency upon removal from furnace
  - Different batches of as-received materials have different oxide adhesion strength
- Polished surfaces have less spallation for both batches:
  - Surface quality influences adhesion strength
- Further work in quantifying IC life should consider:
  - Substrate thickness
  - Substrate chemistry composition/thermal mechanical processing parameters
  - Substrate surface quality

## Accomplishment: Examined Effects of Shot Peening on Oxide Adhesion upon Cooling for SS441



Surface roughness	measurements of	shot-pe	ened sa	mples
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Profile	Ra (µm)	Rq (µm)	Rz (µm)
1	2.79	3.49	24.23
2	2.95	3.67	21.03
3	3.00	3.80	24.88
Mean	2.91	3.65	23.38
Std Dev	0.11	0.16	2.06





- Surface modification through mechanical shot peening *dramatically* reduces the tendency for oxide scale spallation during cooling:
  - Surface modification through cold work/mechanical work
  - Higher surface roughness
    - 10 times rougher than a polished surface
  - Surface residual stress
  - Removal of edge spallation:
    - Reduced free-standing length of oxide layer
    - Increased critical buckling load
    - Decreased cooling induced interfacial shear stress

# **Conclusions & Ongoing Work**

#### Conclusions

- Speed and capabilities of SOFC-MP were improved
- Cathode contact paste stresses were evaluated and a sintering model was developed
- An EC model to simulate pressurized SOFC was developed
- Seal mechanical properties continue to be characterized and modeling was used to evaluate novel sealants
- SOFC design document is completed

## **Ongoing Work**

- Release of the SOFC design document
- Release of 2D SOFC-MP
- Develop a modeling framework to examine cell electrochemistry and secondary reactions
- Characterization of contact paste mechanical strengths
- Simulation of contact paste development and cell load paths in SECA test cell geometry
- Develop modeling capabilities and supporting experiments to evaluate feasibility of advanced sealing concepts

